

IN THE CLAIMS:

1. **(Original)** An end station for an ion implanter, comprising
a vacuum chamber arranged to receive an ion beam
extending along a predetermined beam path in said chamber and having
a chamber wall,
a wafer holder for holding a wafer in a wafer plane,
a scanning arm having a distal end supporting the wafer
holder within the vacuum chamber and a proximal end attached to the
chamber wall,
said scanning arm having at least first and second rotary
joints providing articulation of the arm to permit movement of said
substrate holder in two orthogonal scan directions in a scan plane
transverse to said beam path,
and a scanning arm driver operative to move said substrate
holder in said scan plane in a desired two dimensional scan pattern
relative to said beam path.
2. **(Original)** An end station as claimed in Claim 1, including a
third rotary joint mounting said substrate holder at said distal end of the
scanning arm and having an axis of rotation normal to said wafer plane.
3. **(Currently amended)** An end station as claimed in, ~~either of~~
~~Claims 1 and 2~~claim 1, including a fourth rotary joint mounting said
proximal end of said scanning arm to said chamber wall and having an
axis of rotation parallel to said scan plane, whereby rotation of the
scanning arm at said fourth rotary joint rotates said scan plane relative to
said beam path.

4. **(Currently amended)** An end station as claimed in ~~any preceding claim~~ claim 1 wherein said first and second rotary joints have axes perpendicular to said wafer plane, whereby said scan plane is parallel to said wafer plane.

5. **(Original)** An end station as claimed in Claim 3, wherein said first and second rotary joints have axes perpendicular to said wafer plane, and the axis of said fourth rotary joint lies in said wafer plane.

6. **(Original)** An end station as claimed in Claim 5, wherein the axis of said fourth rotary joint intercepts said beam path.

7. **(Currently amended)** An end station as claimed in ~~either of Claims 5 and 6~~ claim 5, wherein the axis of said fourth rotary joint is perpendicular to said beam path.

8. **(Original)** An end station as claimed in Claim 2, wherein said first and second rotary joints have axes perpendicular to said wafer plane, and said scanning arm driver is operative to drive said third rotary joint so as to maintain the orientation of the wafer holder constant during said desired scan pattern.

9. **(Currently amended)** An end station as claimed in ~~any preceding claim~~ claim 1, wherein said scan arm driver is operative to provide a linear orthogonal raster scan pattern of the substrate holder relative to the beam path, comprising parallel linear scans of the wafer holder across the beam path separated by a predetermined scan pitch.

10. **(Currently amended)** An end station as claimed in ~~any preceding claim~~ claim 1, wherein said scanning arm driver comprises respective first and second motors driving said first and second rotary

joints, and a motor controller controlling said first and second motors to provide said desired scan pattern.

11. **(Original)** A method of moving a workpiece in a desired two-dimensional scan pattern, comprising

mounting the workpiece on a workpiece holder at the distal end of a scanning arm with at least two rotary joints providing articulation of the arm to permit movement of said holder in two orthogonal scan directions in a scan plane,

and driving the scanning arm to move said holder in said scan plane in said desired two dimensional scan pattern.